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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Im-soo PARK, et al.	Art Unit: 1746
Serial No.: 10/685,515	Examiner: Saeed T. Chaudhry
Filed: October 16, 2003	*Confirmation No.: 8169*
For: APPARATUS FOR CLEANING SEMICONDUCTOR WAFER INCLUDING HEATING USING A LIGHT SOURCE AND METHOD FOR CLEANING WAFER USING THE SAME (AS AMENDED)	Attorney Docket No.: 249/255 DIV

REPLY UNDER 37 C.F.R. § 1.116

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Sir:

INTRODUCTORY COMMENTS

In response to the Office Action Made Final mailed on October 30, 2006, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

A Listing of the Claims are reflected in a listing of claims, which begins on page 2 of this paper; and

Remarks begin on page 5 of this paper.